

1/27

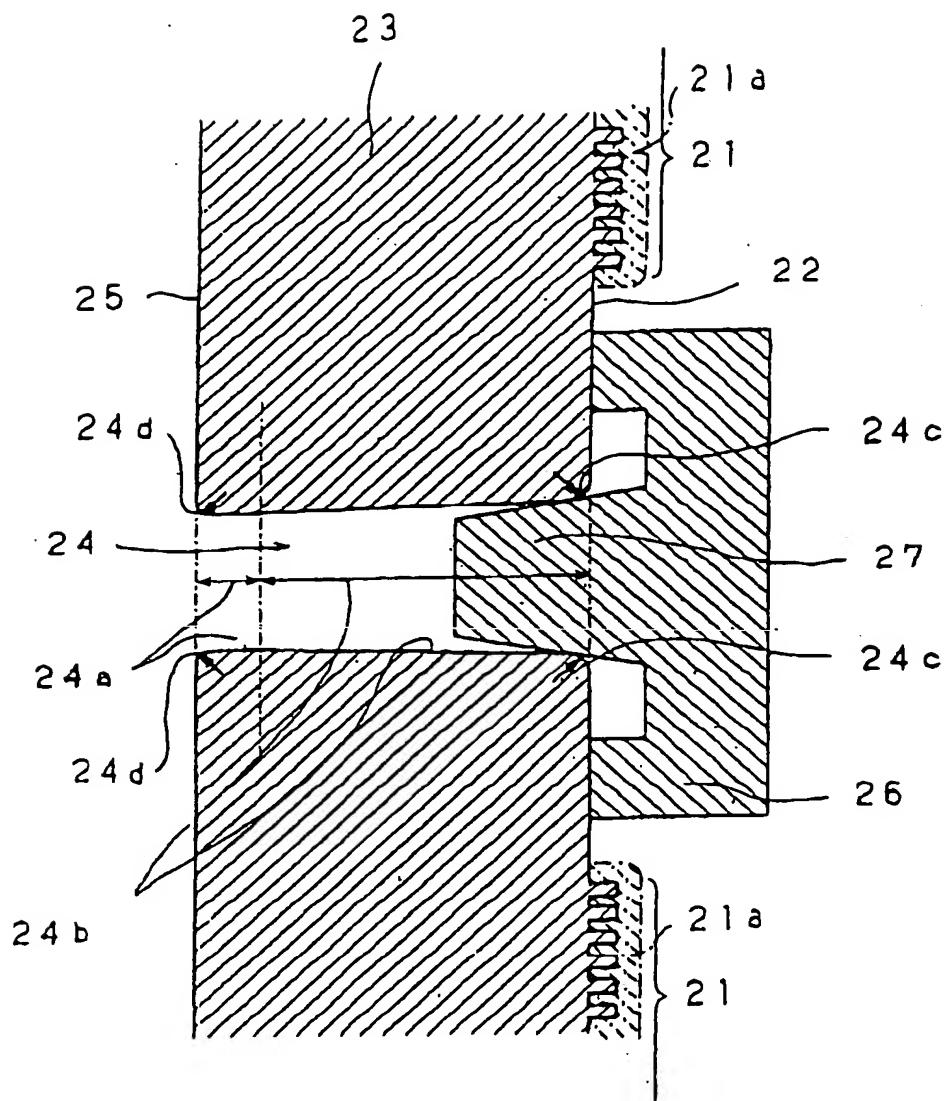


Fig.1

2/27

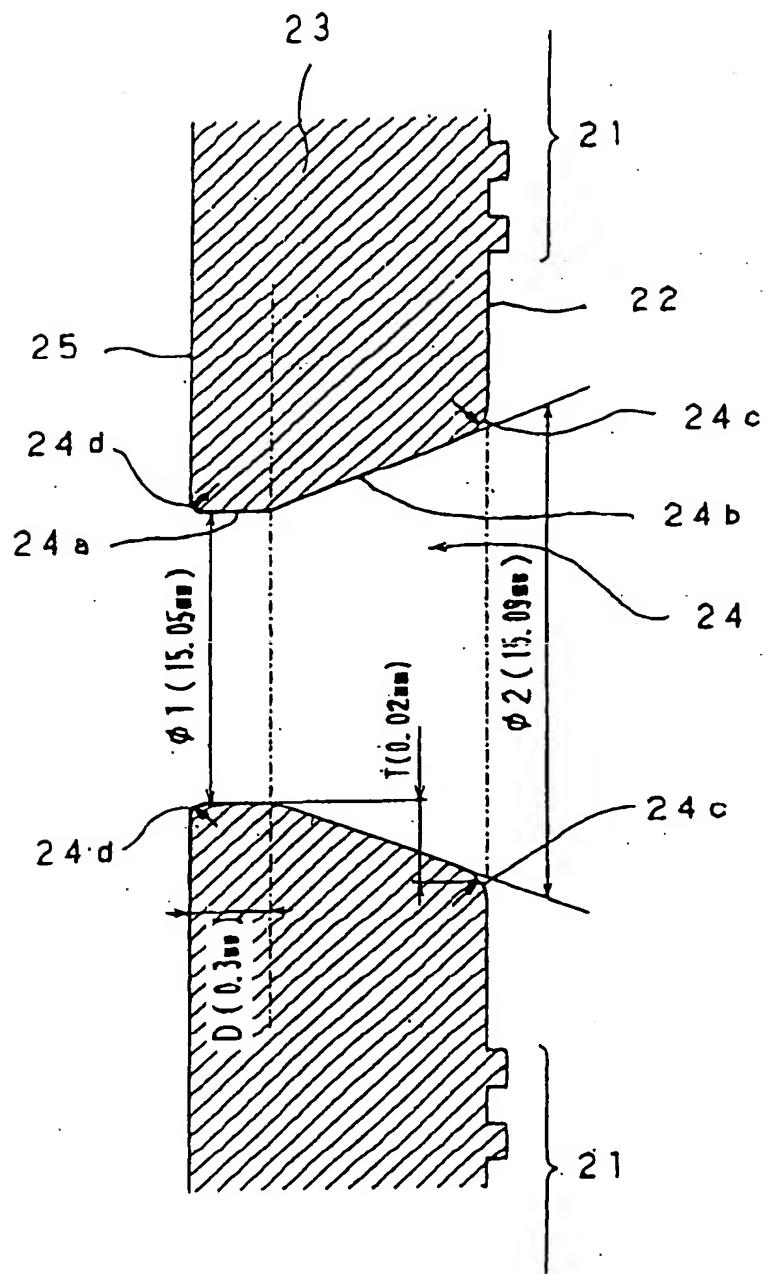


Fig.2

3/27

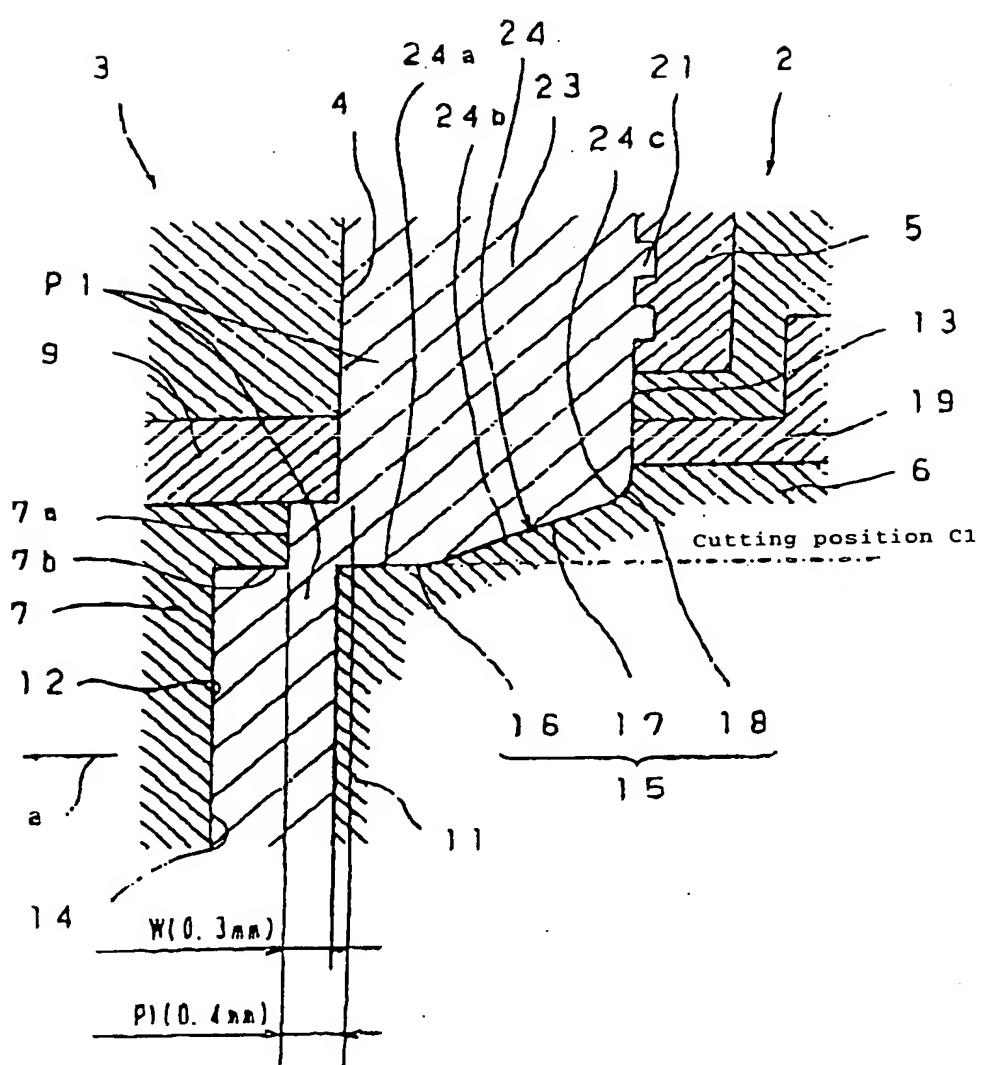


Fig.3

4/27

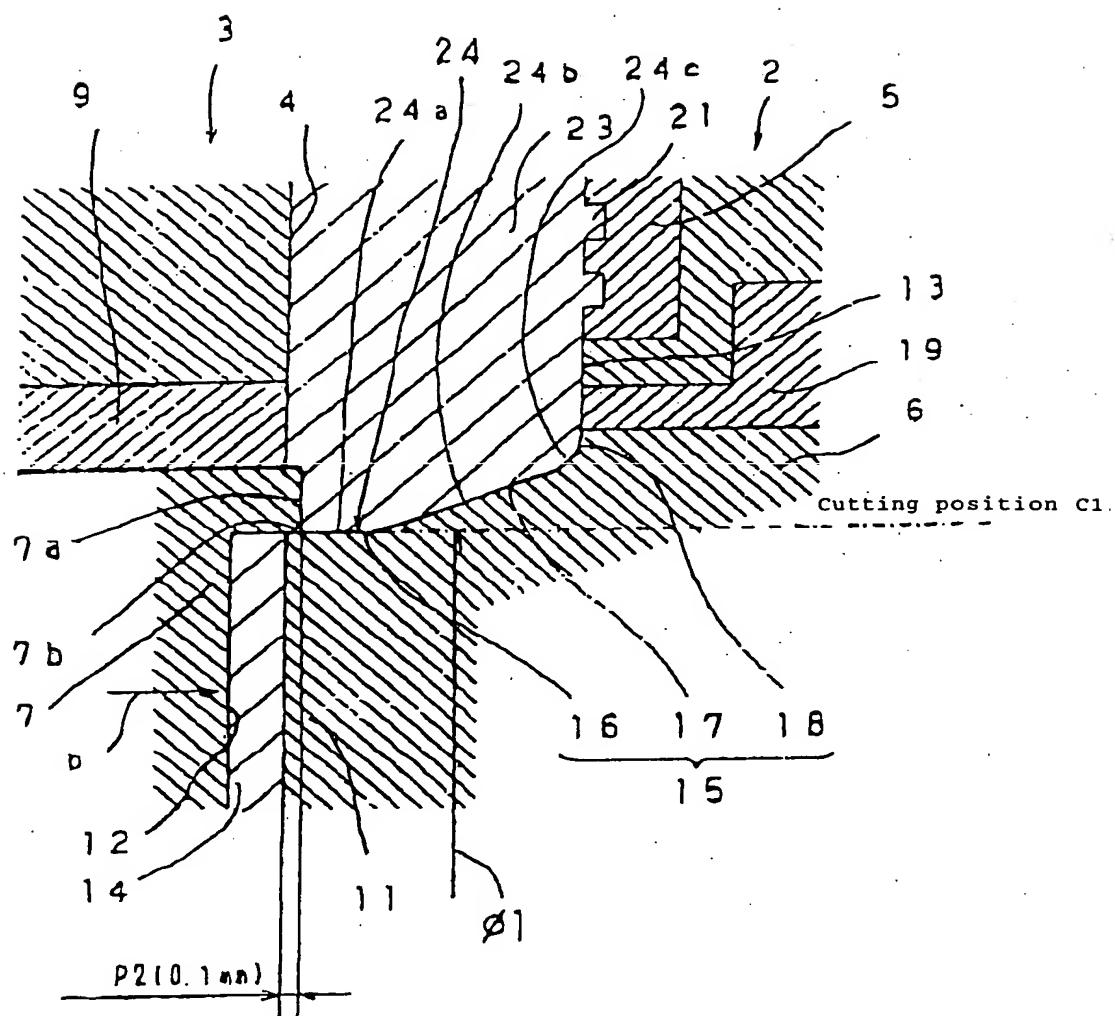


Fig.4

5/27

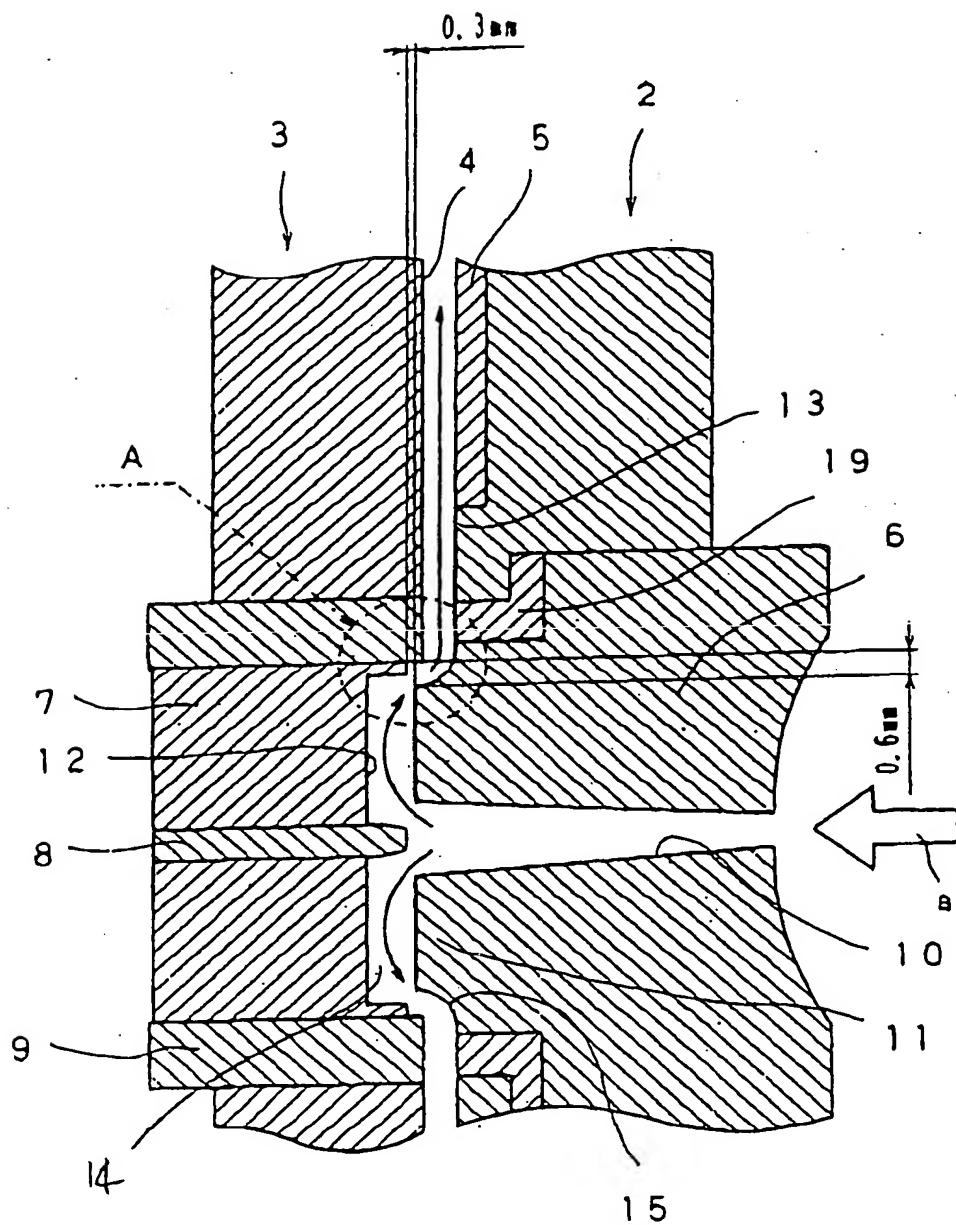


Fig.5

6/27

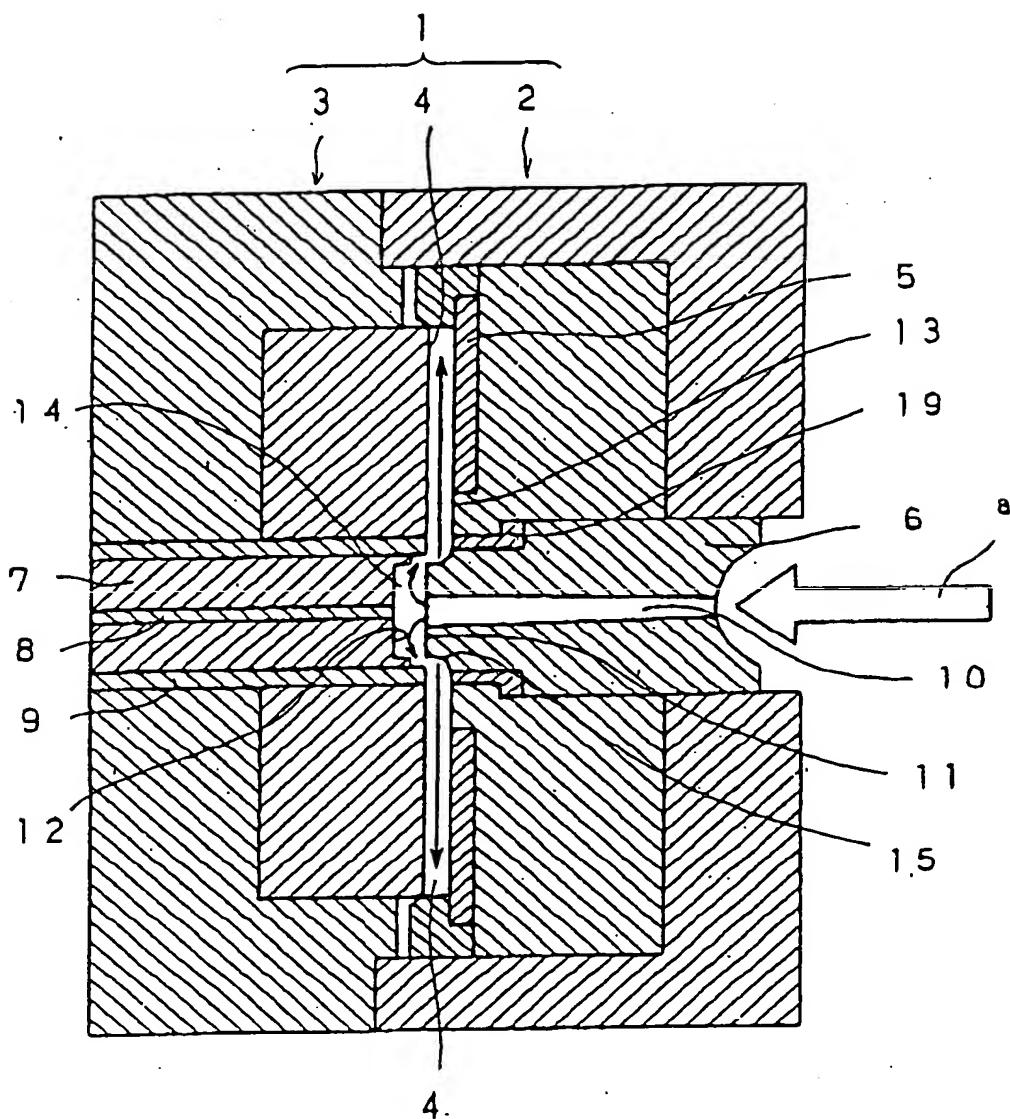


Fig.6

7/27

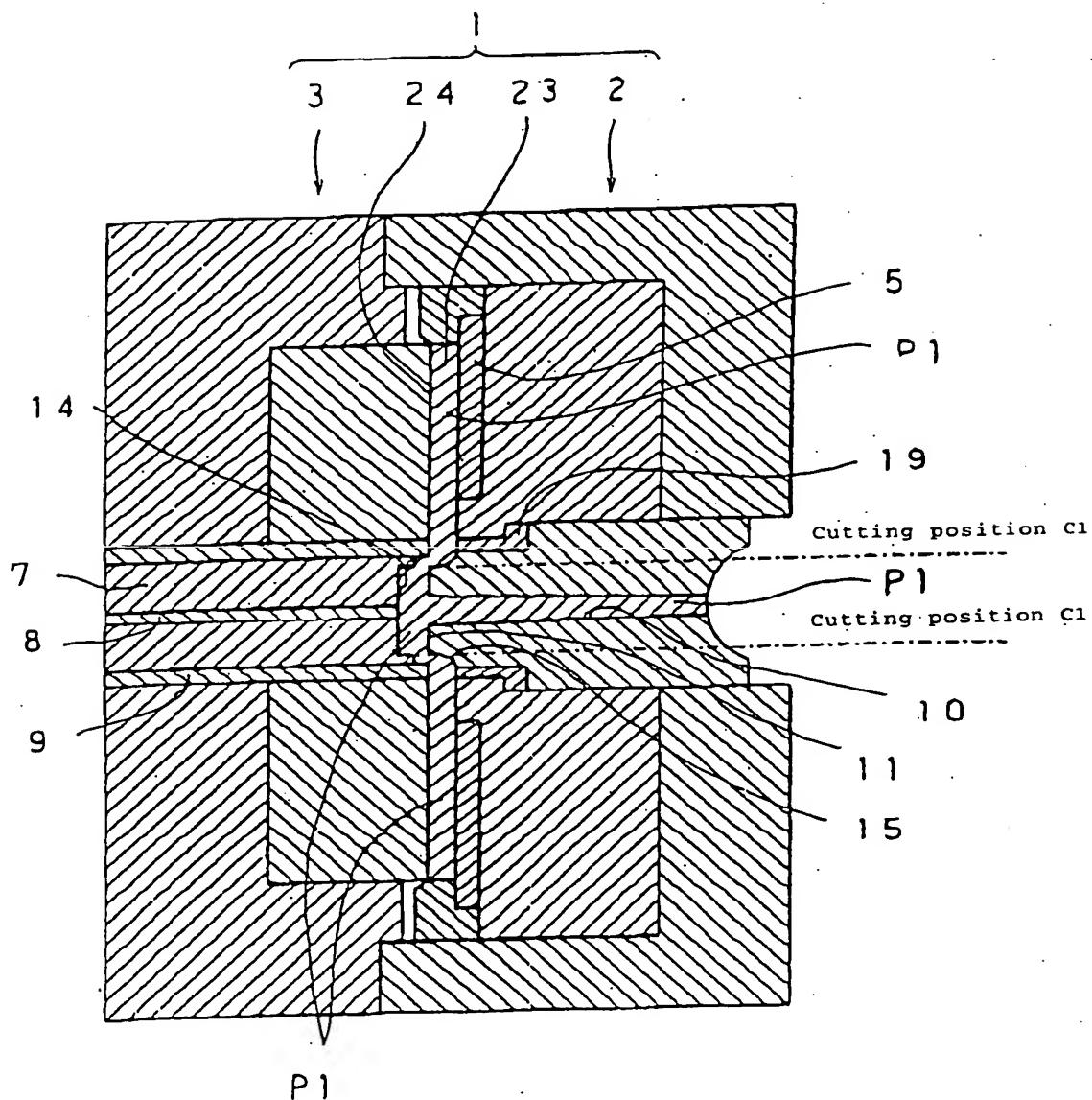


Fig.7

8/27

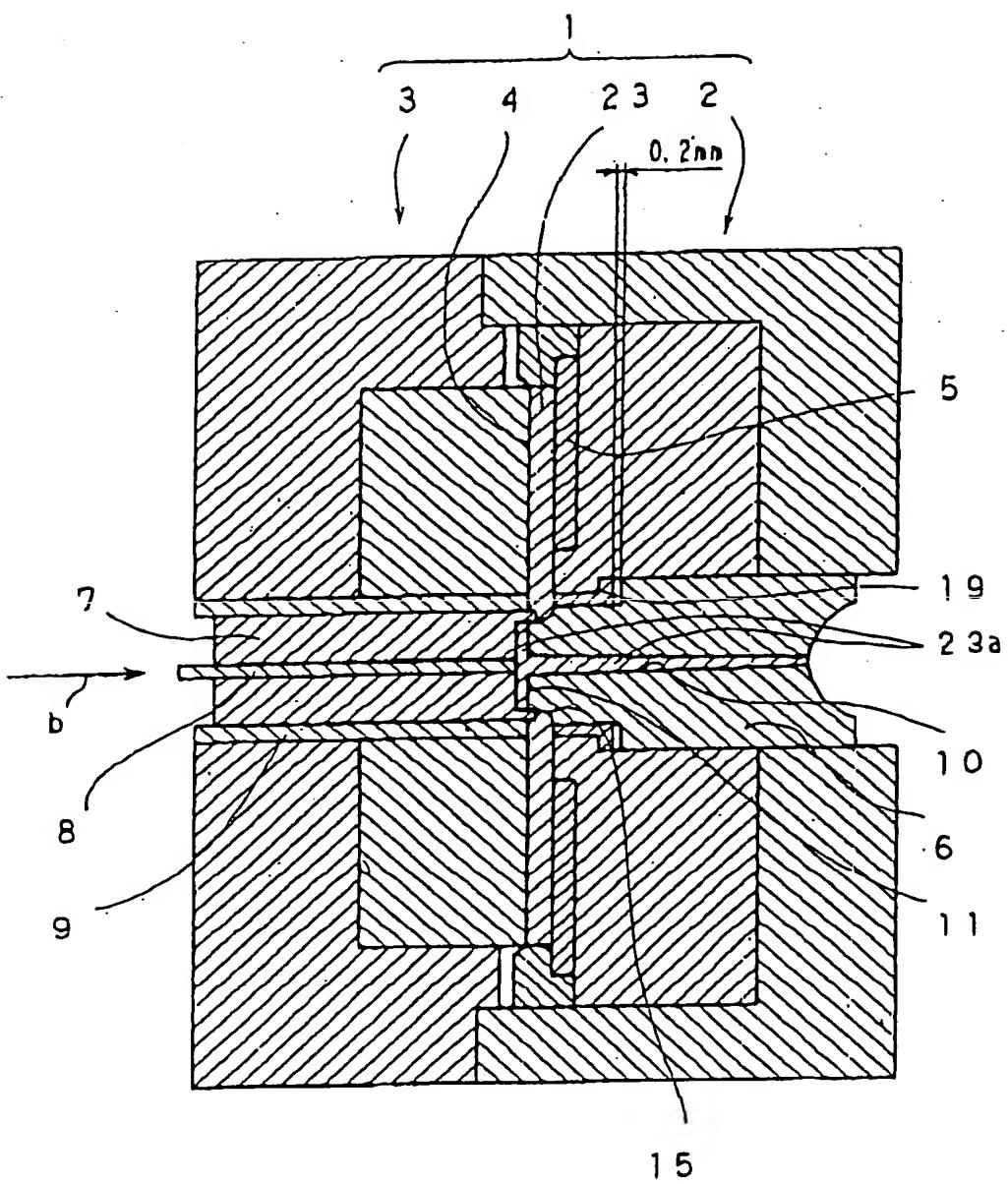


Fig.8

9/27

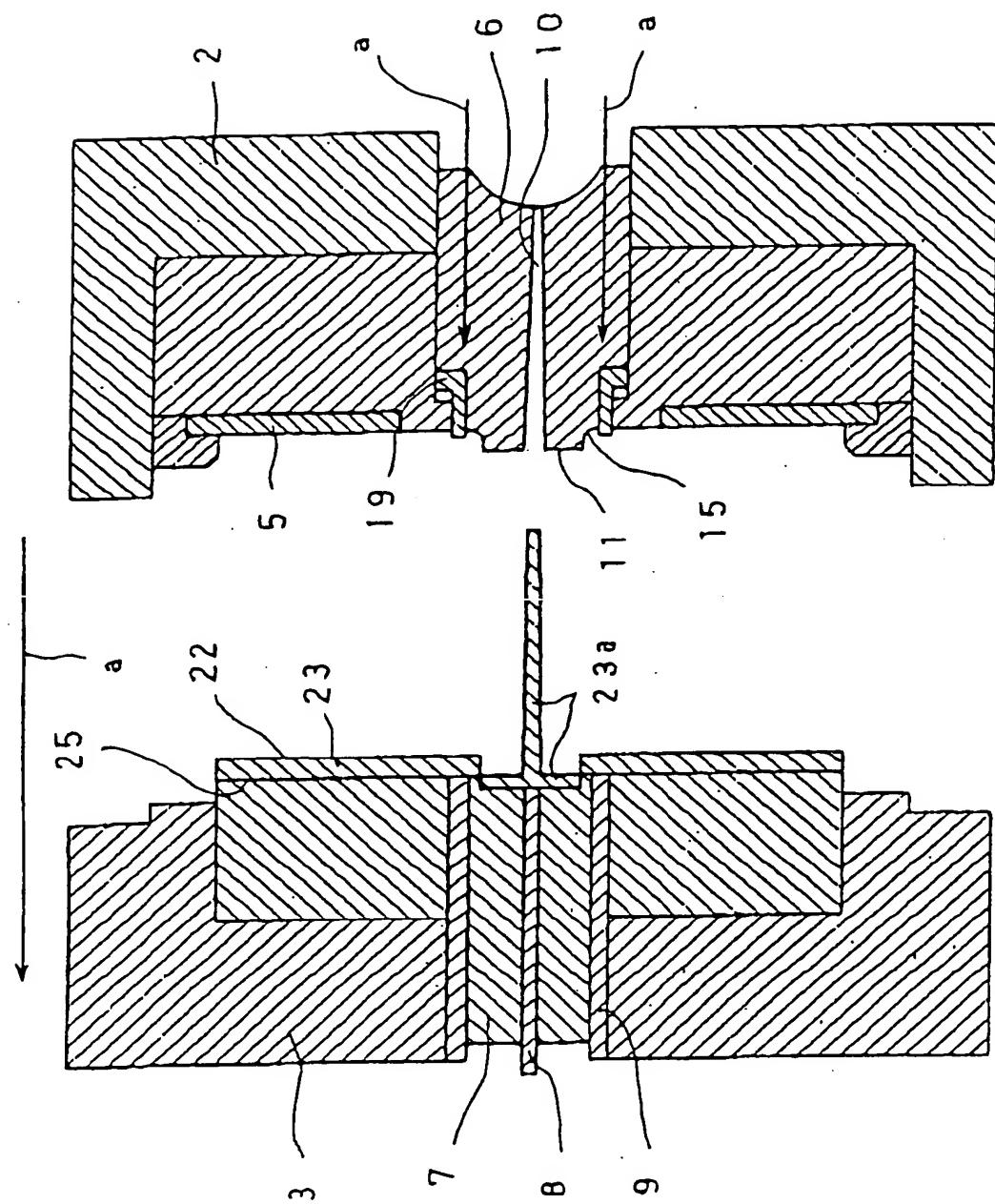


Fig.9

10/27

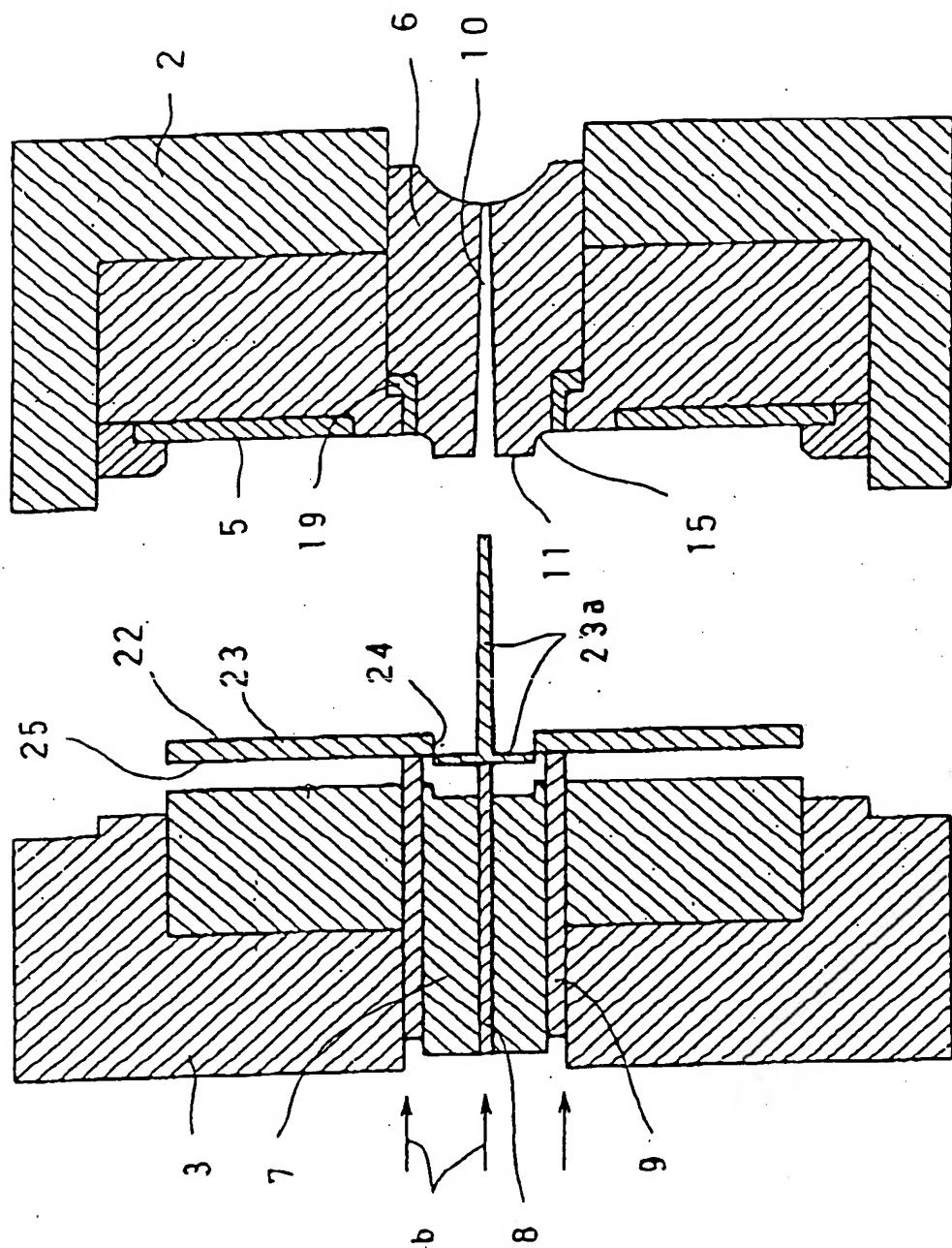


Fig.10

11/27

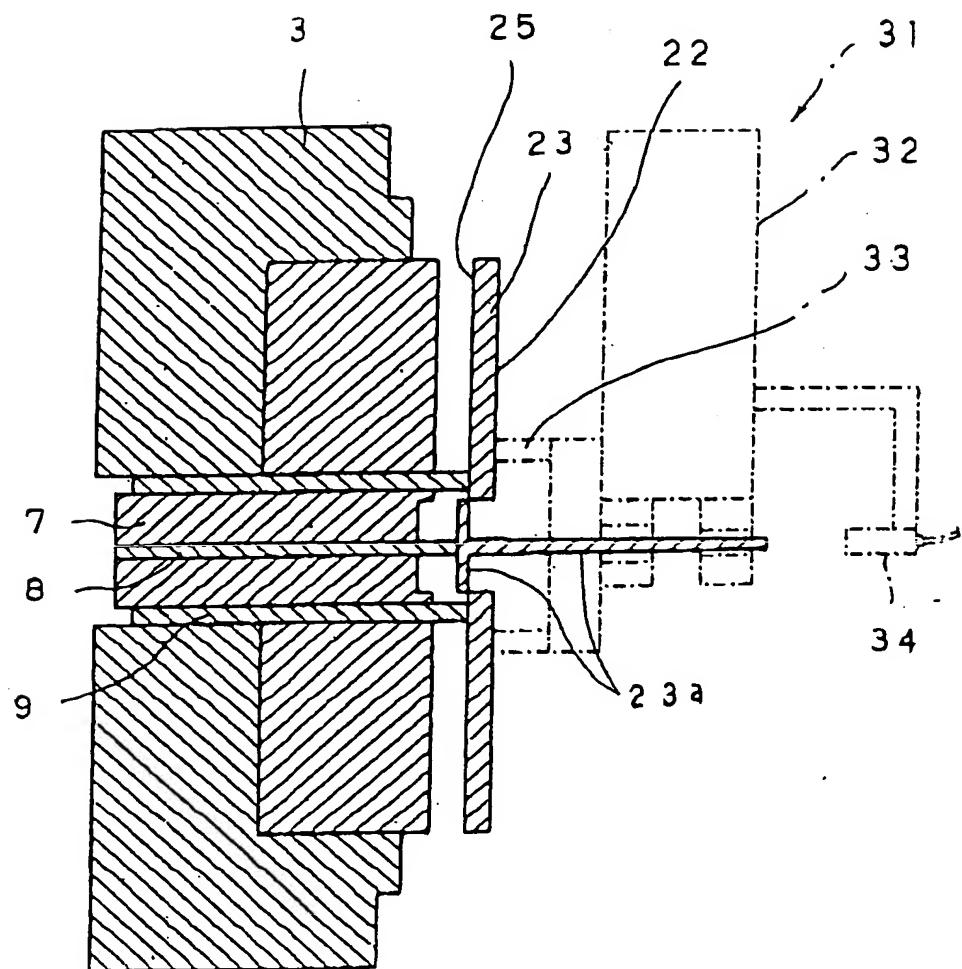


Fig.11

12/27

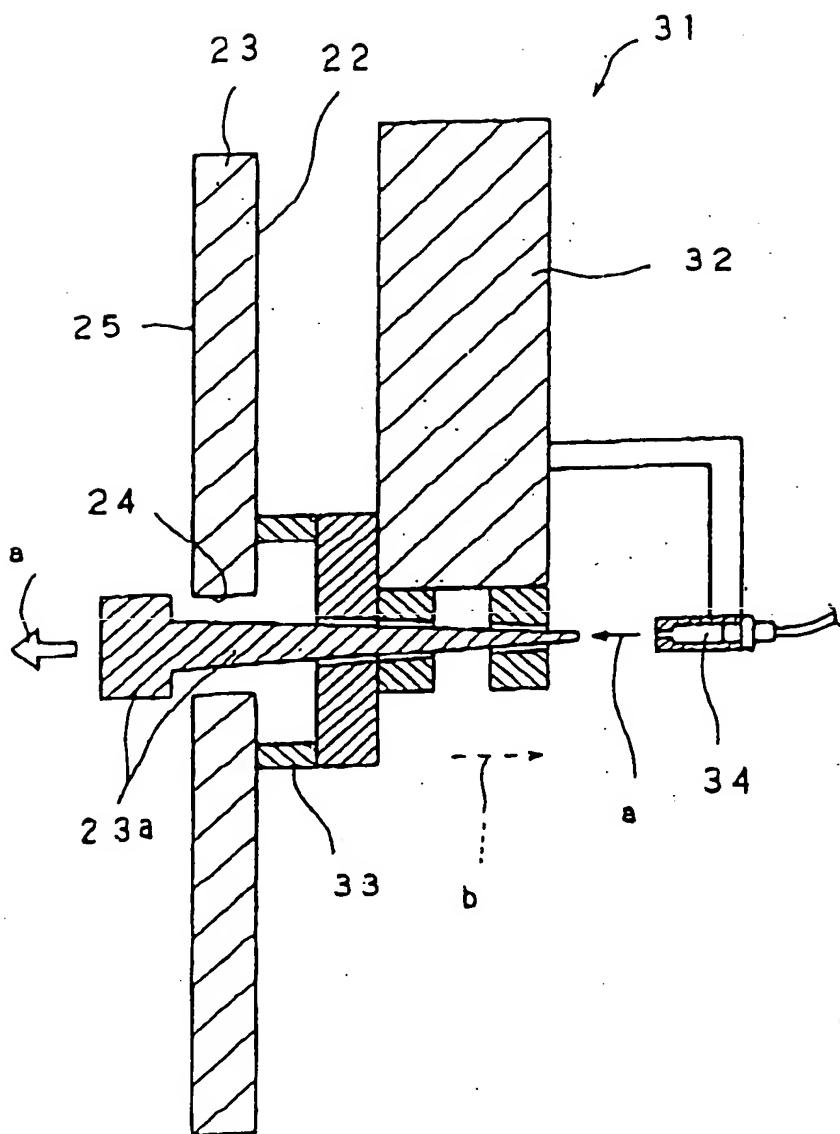


Fig.12

13/27

	Example 1	Comparative Example 1	Comparative Example 2	Comparative Example 3
Substrate of the present invention	Movable-side stamper substrate	Fixed-side stamper substrate	Comparative Example 2 removed by reamer	
Ten measurements of eccentricity amount:	20~30 μ m	20~30 μ m	15~70 μ m	20~30 μ m

Fig.13

14/27

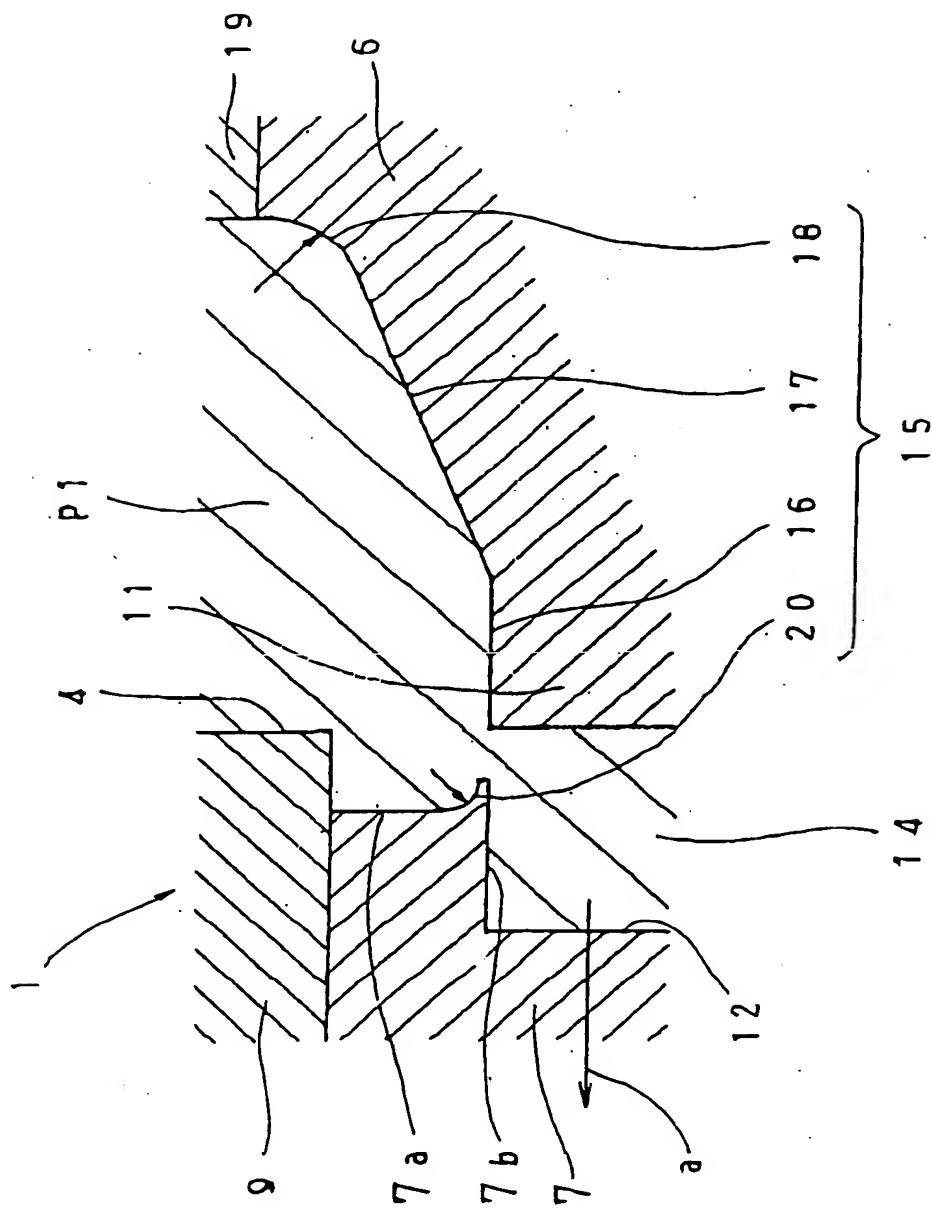


Fig.14

15/27

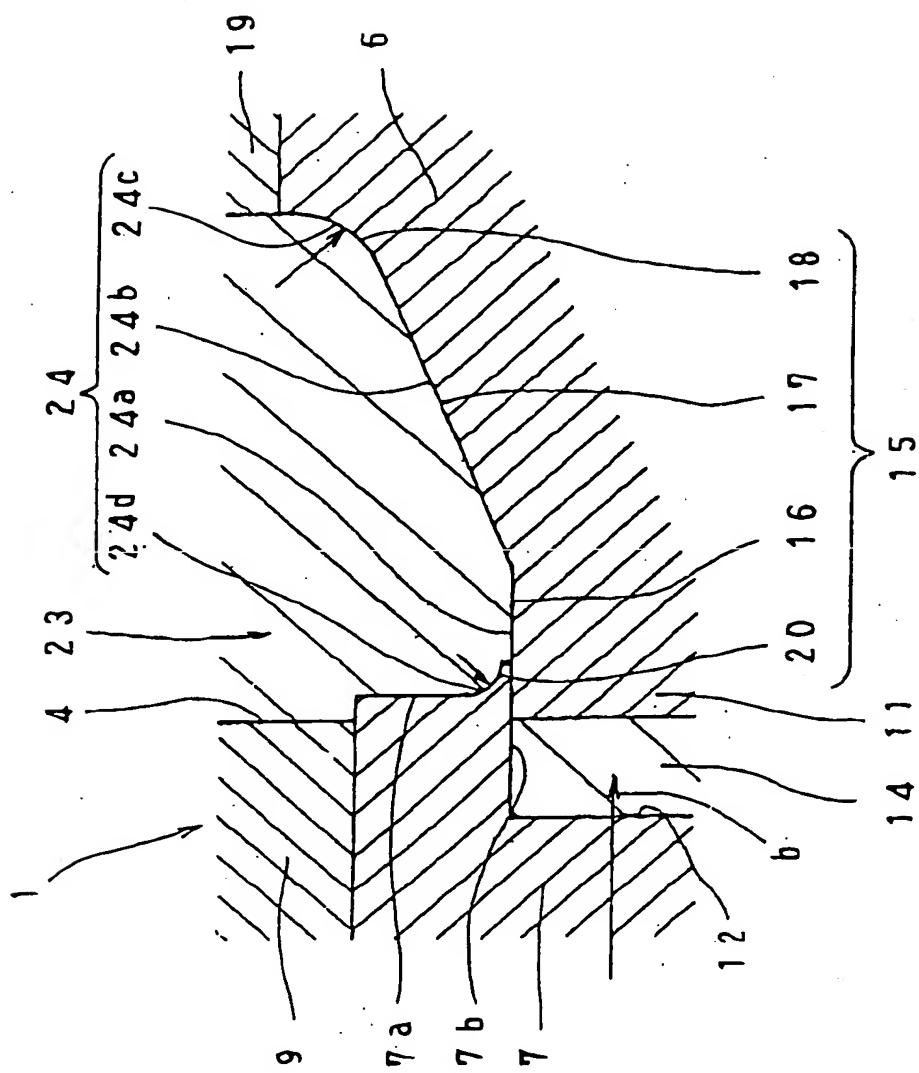


Fig.15

16/27

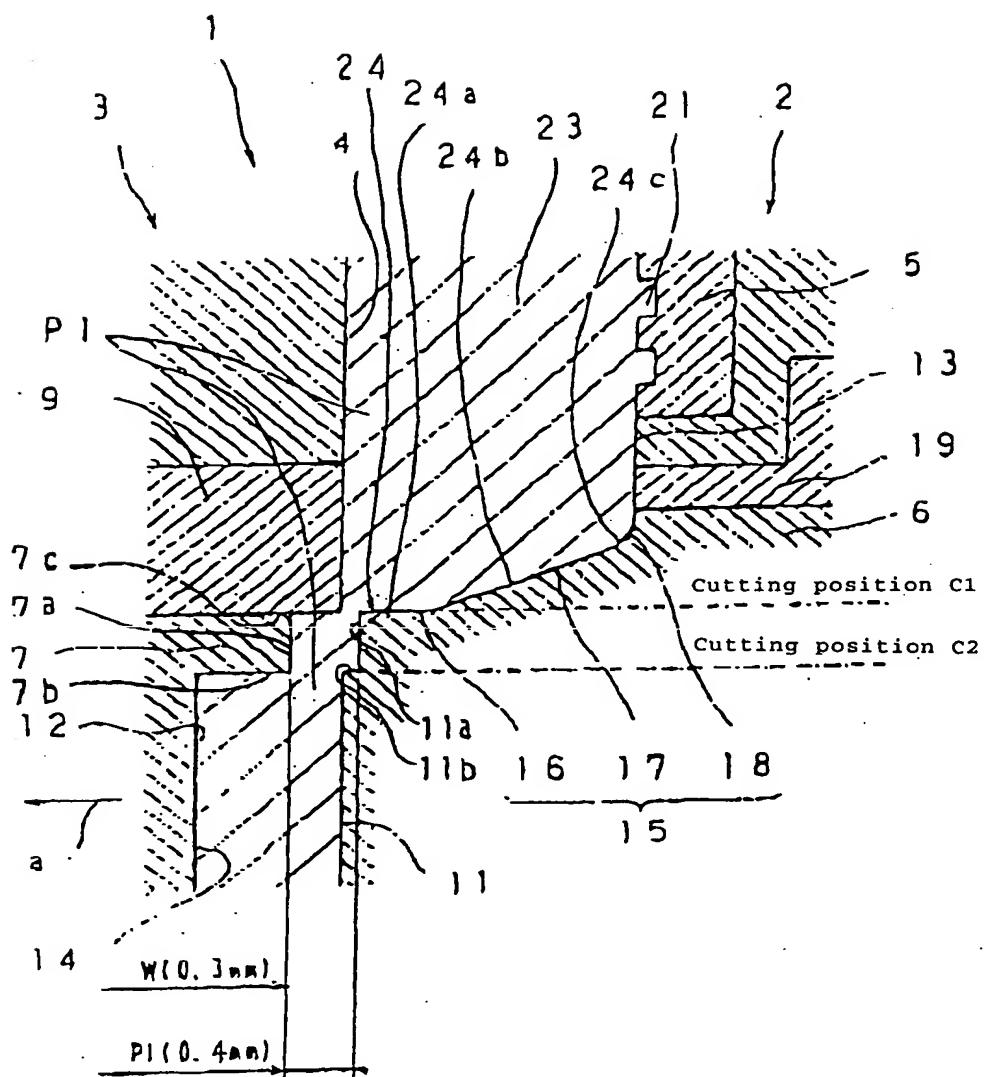


Fig.16

17/27

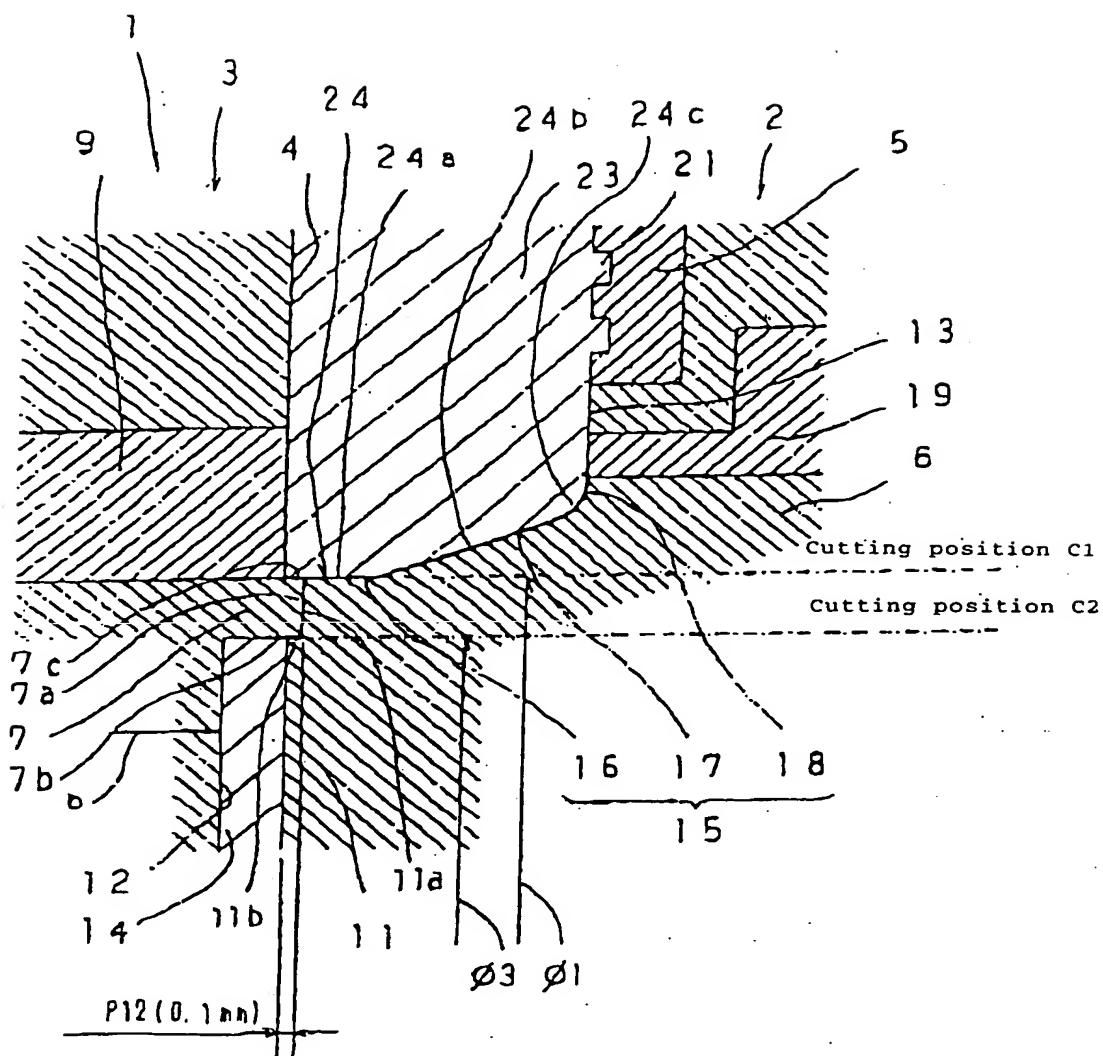


Fig. 17

18/27

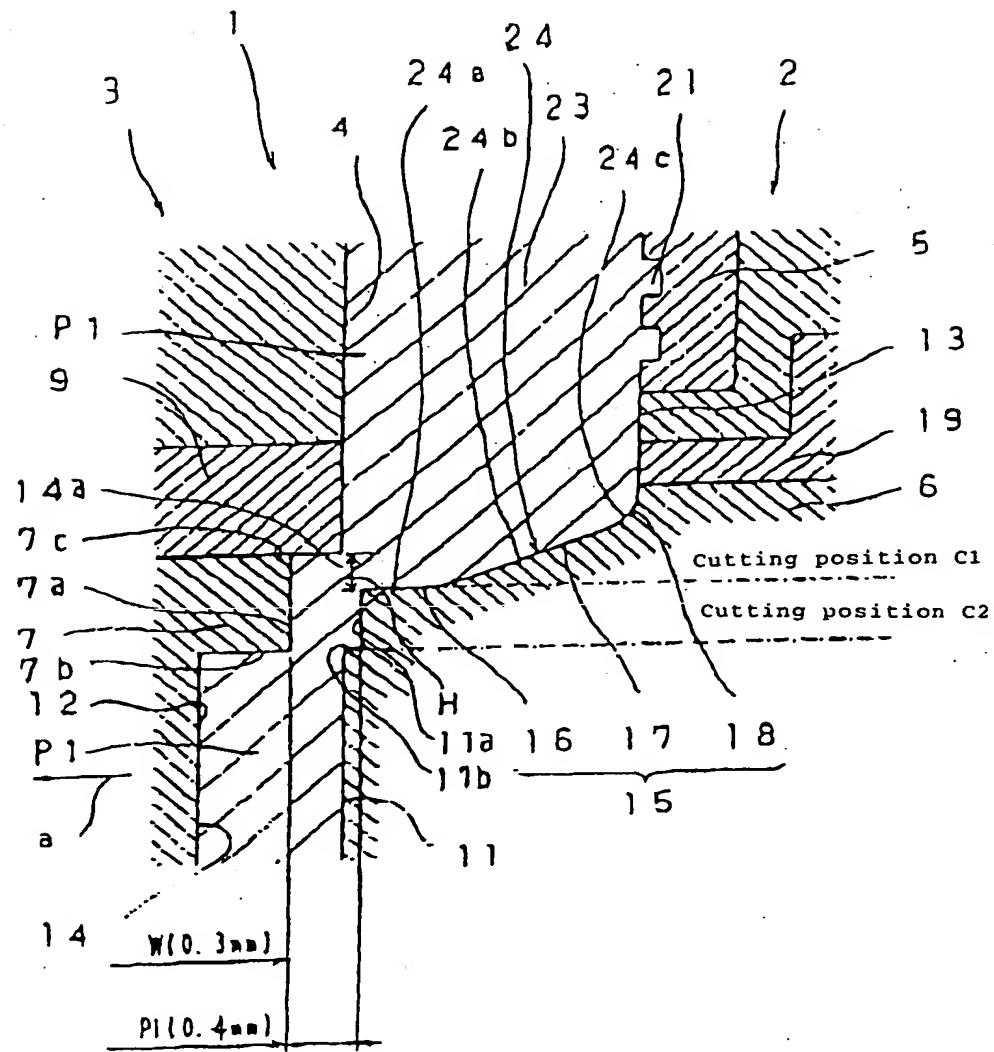


Fig.18

19/27

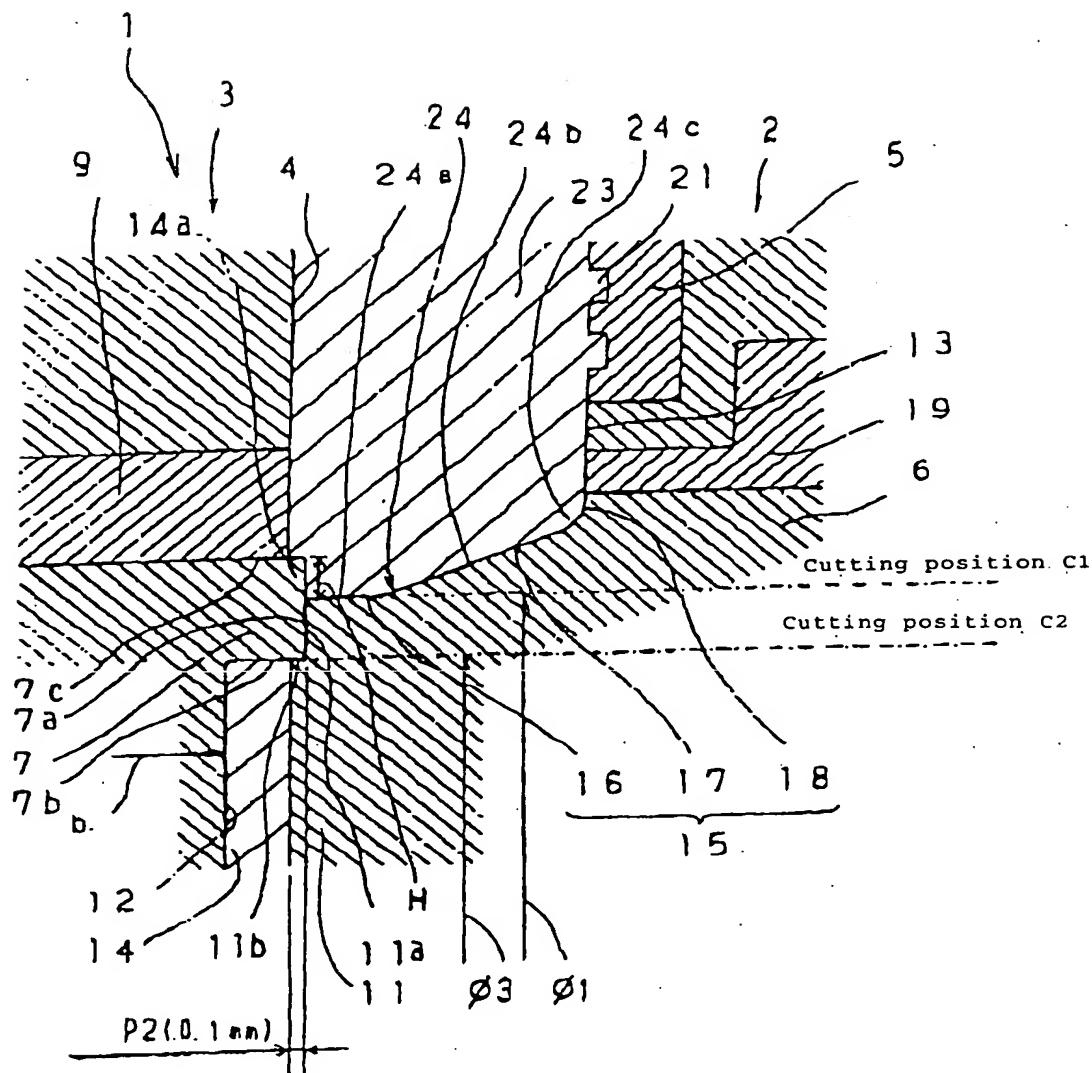


Fig.19

20/27

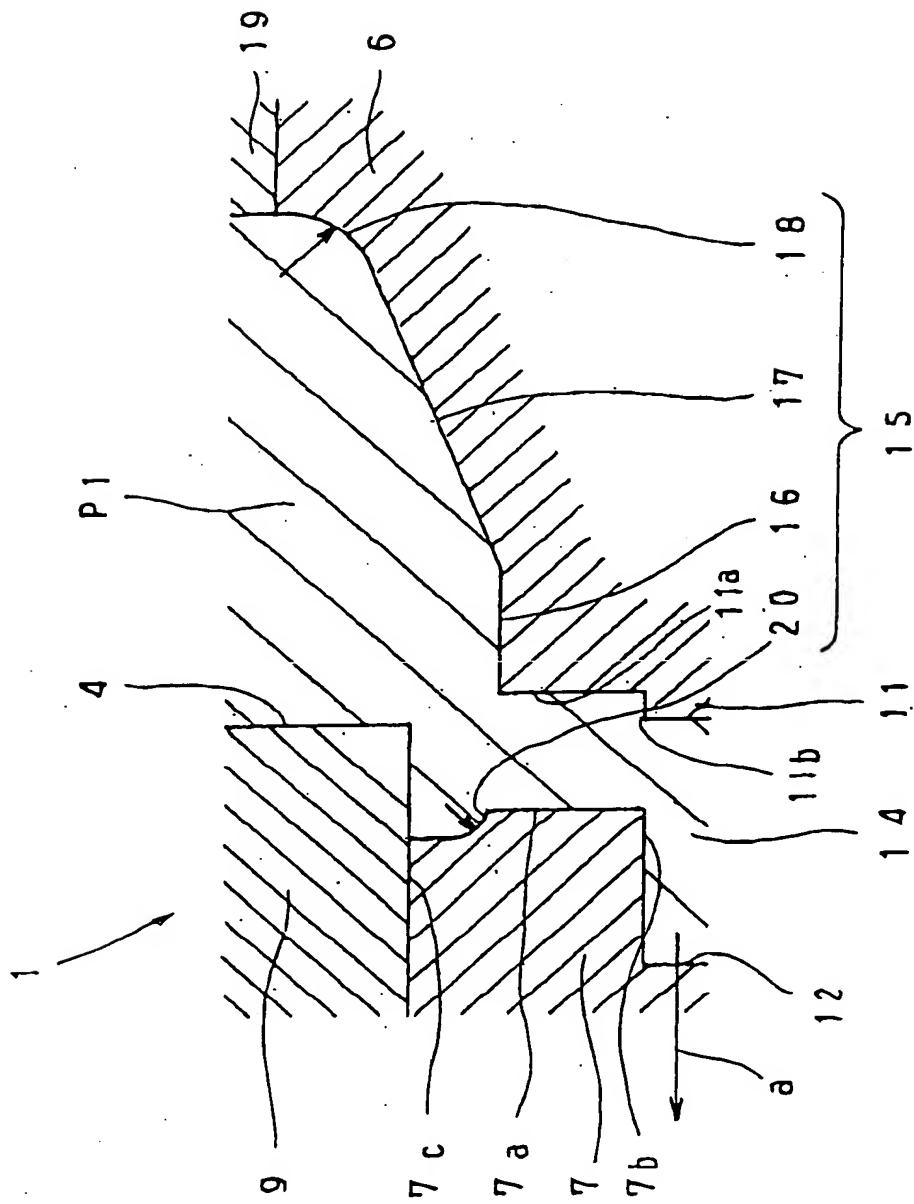


Fig.20

21/27

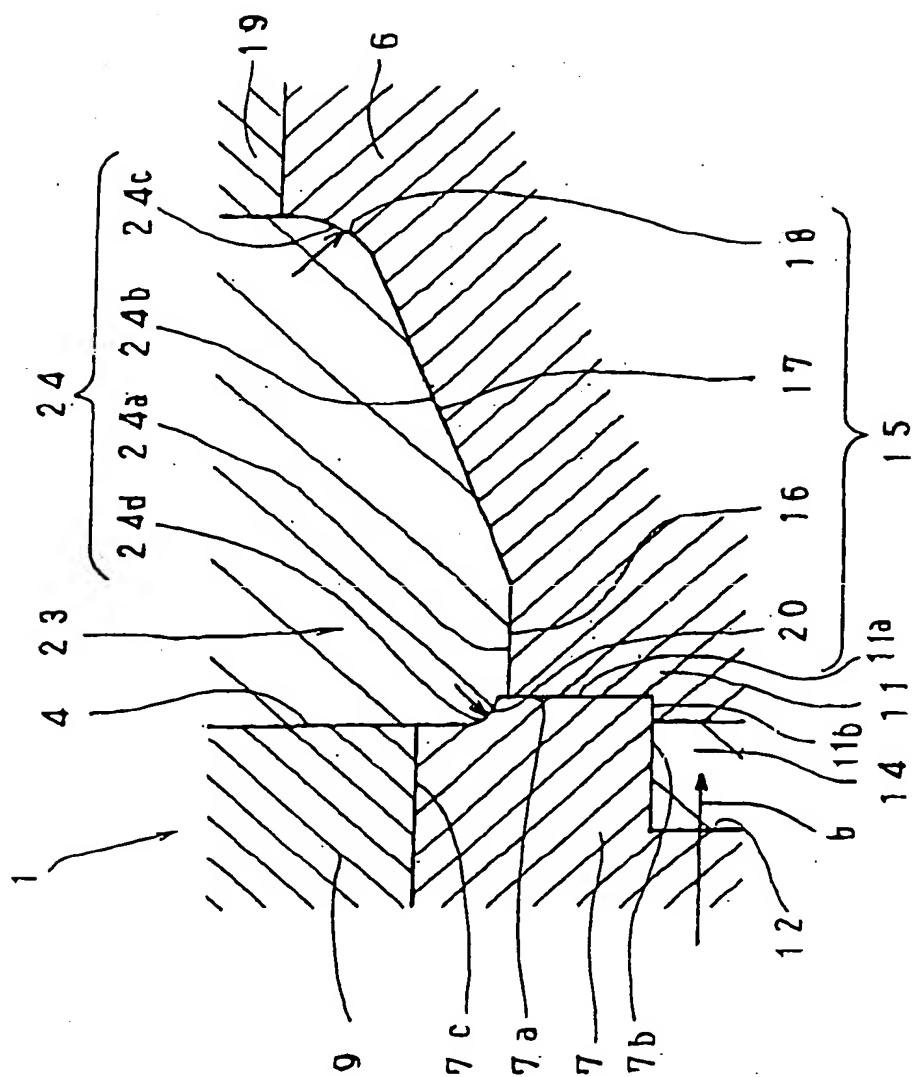


Fig.21

22/27

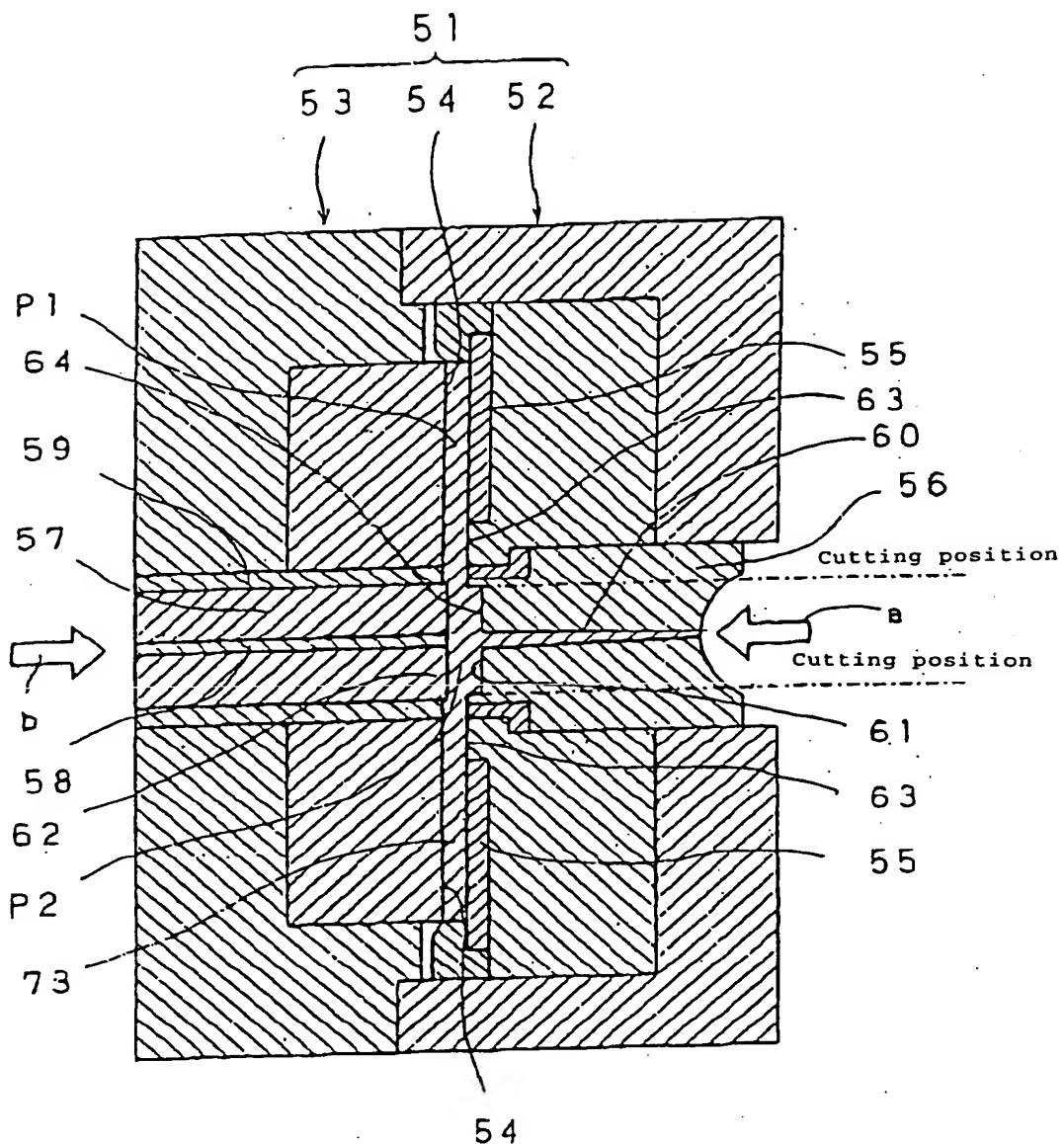


Fig.22

23/27

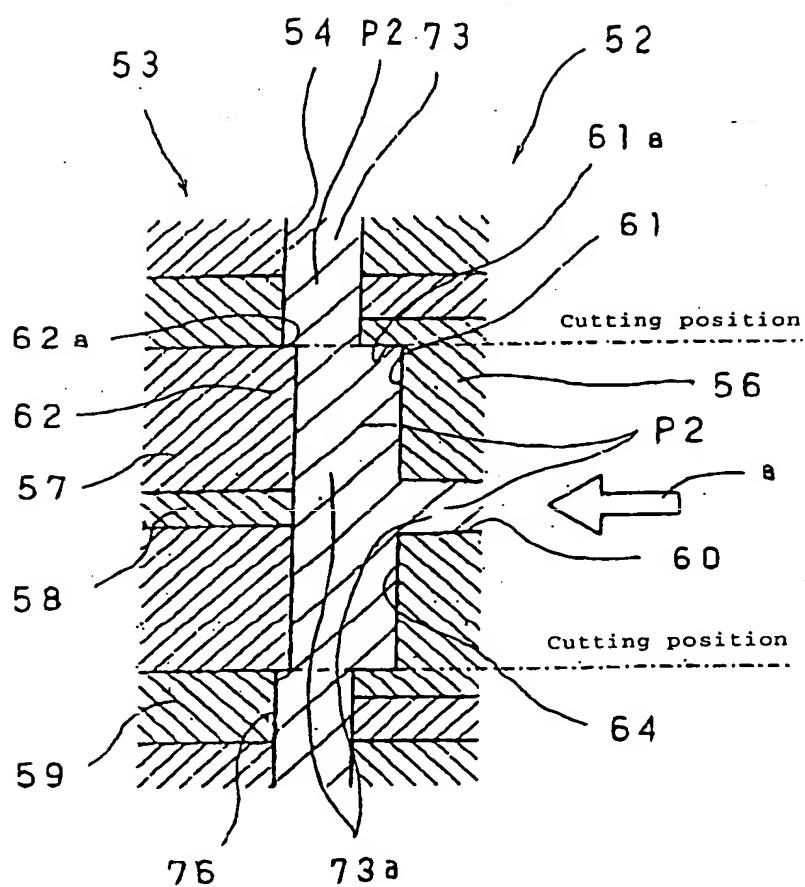


Fig.23

24/27

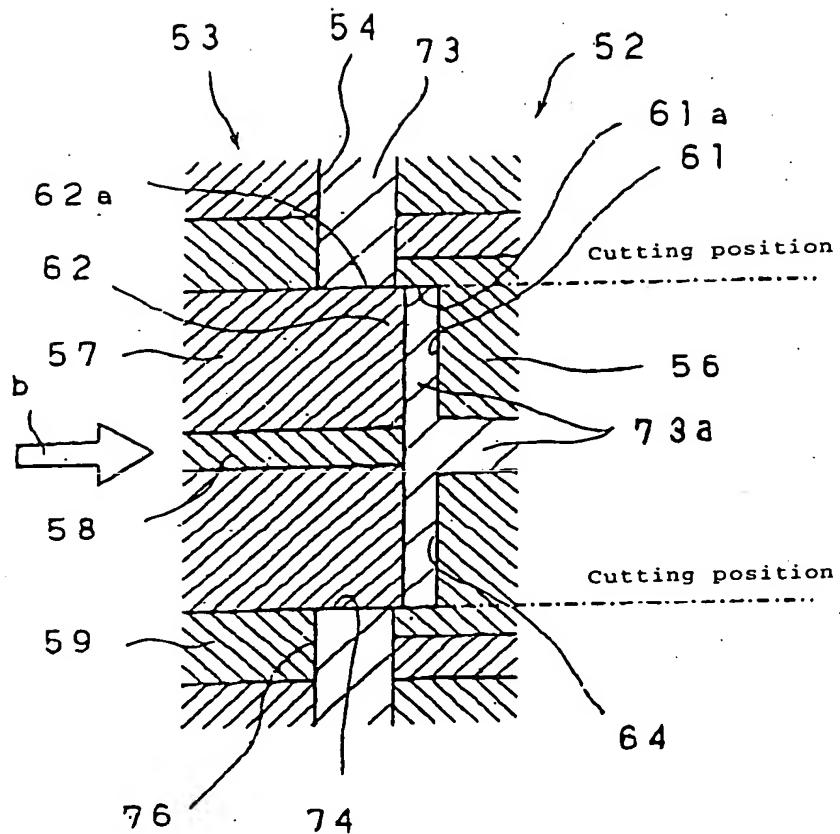


Fig.24

25/27

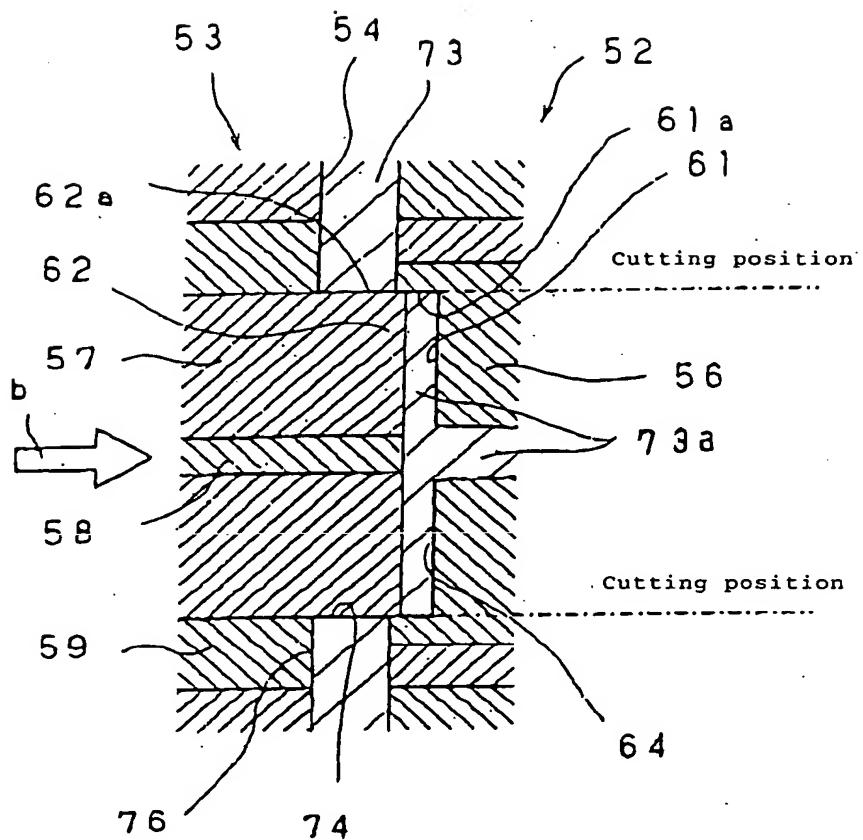


Fig.25

26/27

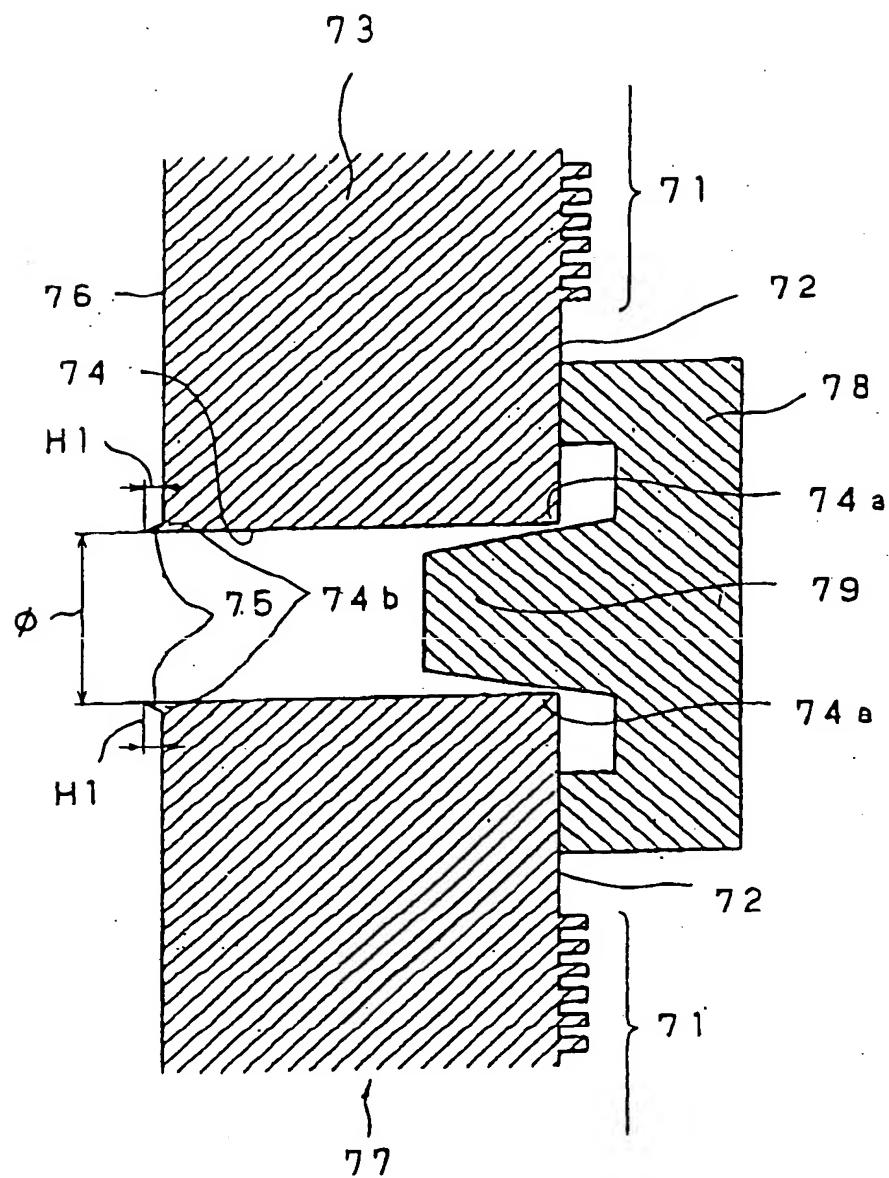


Fig.26

27/27

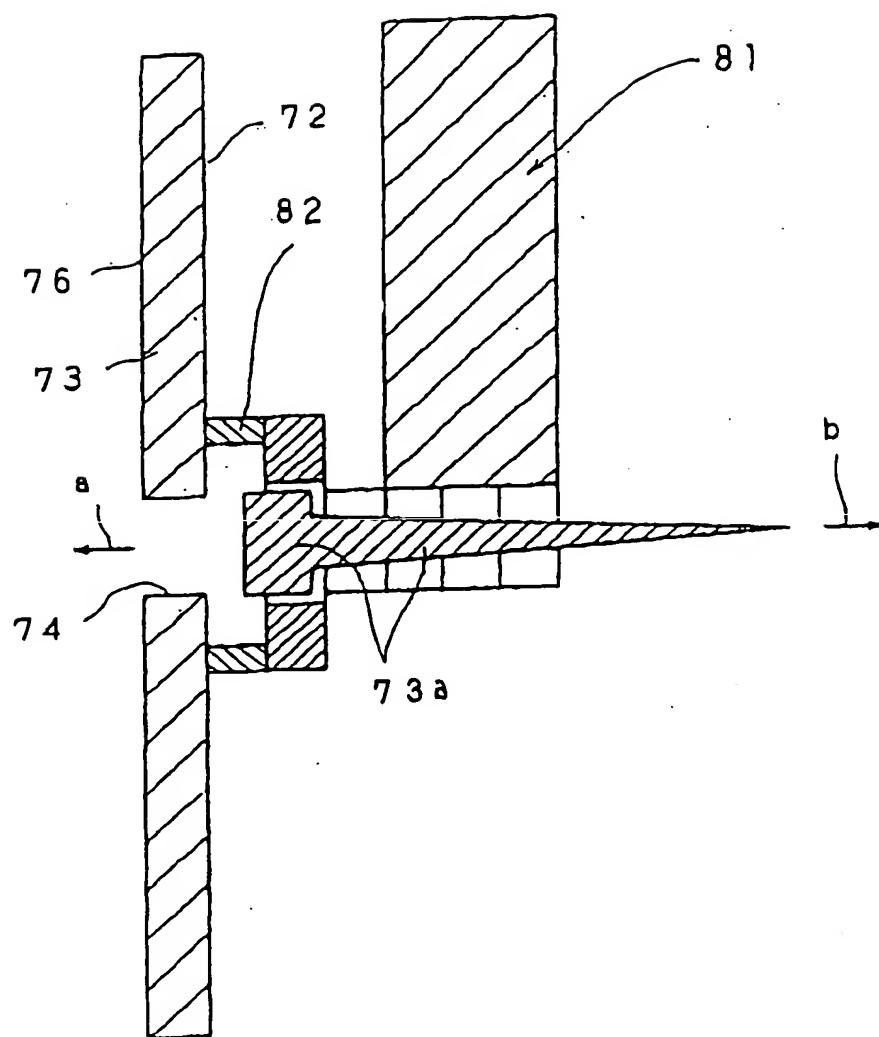


Fig.27